

## **IN THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended)      A method of forming a thin film,  
wherein a sample boat having an EL material contained therein, a substrate having an electrode provided thereon, and a mask between the sample boat and the substrate are provided,  
wherein the EL material is made to be in a vapor state in the sample boat,  
wherein the EL material in the vapor state is discharged from the sample boat toward the substrate, [[and]]

wherein a voltage is applied to the mask, and

wherein the EL material in the vapor state is made to pass through an opening of the mask corresponding to the electrode to deposit the EL material on the electrode on the substrate and form a thin film.

2-17. (Canceled)

18. (New) A method of forming a thin film according to claim 1, wherein the EL material in a vapor state is charged when the EL material is made to be in a vapor state in the sample boat and the EL material in a vapor state is discharged from the sample boat toward the substrate.

19. (New) A method of forming a thin film according to claim 1, wherein the opening in the mask is a gap of blocking portions.

20. (New) A method of forming a thin film according to claim 1, wherein there are a plurality of the masks and different voltages are applied to the respective plurality of masks.

21. (New) A method of forming a thin film according to claim 1, wherein the electrode is a pixel electrode.

22. (New) A method of forming a thin film according to claim 1, wherein the EL material is a low molecular weight material.

23. (New) A method of forming a thin film according to claim 1, wherein the thickness of the thin film is 10nm to 10  $\mu\text{m}$ .

24. (New) A method of forming a thin film according to claim 1, wherein the mask is a conductive wire formed of a conductive material, a mesh-like structure formed of conductive wires, a plate-like structure formed of a conductive material, or a plurality of conductive wires arranged in parallel with one another.

25. (New) A method of forming a thin film according to claim 1, wherein said EL material is an organic material.

26. (New) A method of manufacturing a light emitting device comprising:  
disposing a substrate in a film forming chamber wherein a sample boat having an EL material contained therein is provided in the film forming chamber;

vaporizing said EL material;

directing the vaporized EL material to said substrate wherein a mask having an opening is located between said sample boat and said substrate; and

forming said EL material over said substrate wherein the vaporized EL material passes through said opening of the mask,

wherein the vaporized EL material is electrically charged prior to reaching the mask.

27. (New) A method of manufacturing a light emitting device according to claim 26, wherein said light emitting device is an active matrix light emitting device.

28. (New) A method of manufacturing a light emitting device according to claim 26, wherein said light emitting device is a passive light emitting device.

29. (New) A method of manufacturing a light emitting device comprising:

providing a sample boat having an EL material contained therein in a film formation chamber, wherein said sample boat has an opening;

heating and vaporizing said EL material so that said EL material is discharged from said sample boat through said opening;

directing the vaporized EL material to a substrate wherein a mask having an opening is located between said sample boat and said substrate; and

forming said EL material over the substrate wherein the vaporized EL material passes through said opening of the mask,

wherein the vaporized EL material is electrically charged by applying a voltage through an electrode which is provided at said opening of the sample boat.

30. (New) A method of manufacturing light emitting device according to claim 29, wherein said light emitting device is an active matrix light emitting device.

31. (New) A method of manufacturing a light emitting device according to claim 29, wherein said light emitting device is a passive light emitting device.

32. (New) A method of manufacturing a light emitting device comprising:  
disposing a substrate in a film forming chamber wherein a sample boat having an EL material contained therein is provided in the film forming chamber;  
vaporizing said EL material;  
directing the vaporized EL material to said substrate wherein a mask having an opening is located between said sample boat and said substrate;  
applying a voltage to the mask; and  
forming said EL material over said substrate wherein the vaporized EL material passes through said opening of the mask,  
wherein the vaporized EL material is electrically charged prior to reaching the mask.

33. (New) A method of manufacturing a light emitting device according to claim 32, wherein said light emitting device is an active matrix light emitting device.

34. (New) A method of manufacturing a light emitting device according to claim 32, wherein said light emitting device is a passive light emitting device.

35. (New) A method of manufacturing a light emitting device comprising:  
providing a sample boat having an EL material contained therein in a film formation chamber, wherein said sample boat has an opening;  
heating and vaporizing said EL material so that said EL material is discharged from said sample boat through said opening;  
directing the vaporized EL material to a substrate wherein a mask having an opening is located between said sample boat and said substrate;  
applying a voltage to the mask; and  
forming said EL material over the substrate wherein the vaporized EL material passes through said opening of the mask,  
wherein the vaporized EL material is electrically charged by applying a voltage through an electrode which is provided at said opening of the sample boat.

36. (New) A method of manufacturing a light emitting device according to claim 35, wherein said light emitting device is an active matrix light emitting device.

37. (New) A method of manufacturing a light emitting device according to claim 35, wherein said light emitting device is a passive light emitting device.